

Report on EUDET Mechanics

- *Global Design and composite structures:* **Marc Anduze**
- *Integration Slab and thermal measurements:* **Aboud Falou**
- *Cooling systems and thermal simulations:* **Denis Grondin**
- *Gluing of ASU:* **David Bailey**
- *Interconnect system:* **Maurice Goodrick**

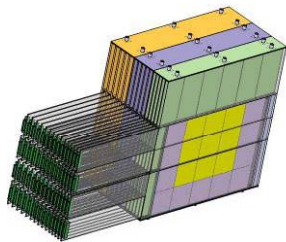


CALICE meeting - Manchester

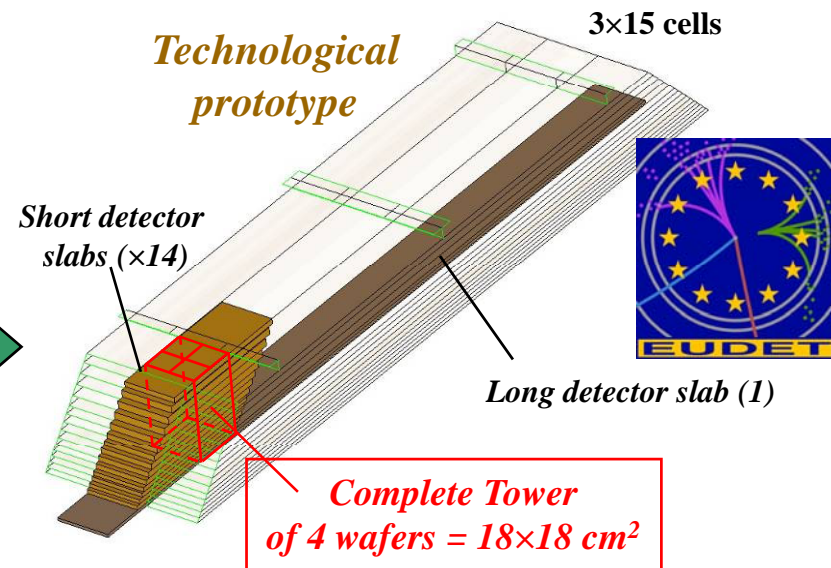
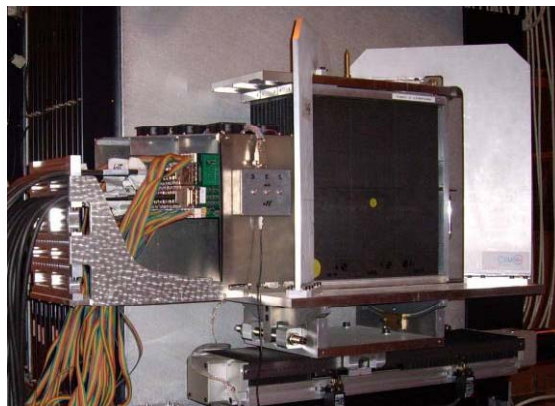


Technological prototype : EUDET module

- Logical continuation to the physics prototype study which validated the main concepts : alveolar structure , slabs, gluing of wafers, integration
- Techno. Proto : study and validation of most of technological solutions wich could be used for the final detector (moulding process, cooling system, sizes of structures,...)
- Taking into account industrialization aspect of process
- Finest cost estimation of one module



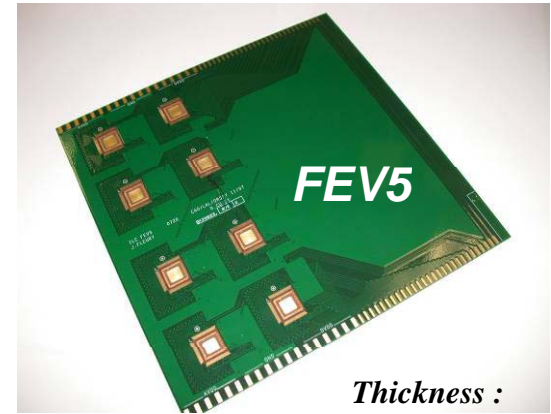
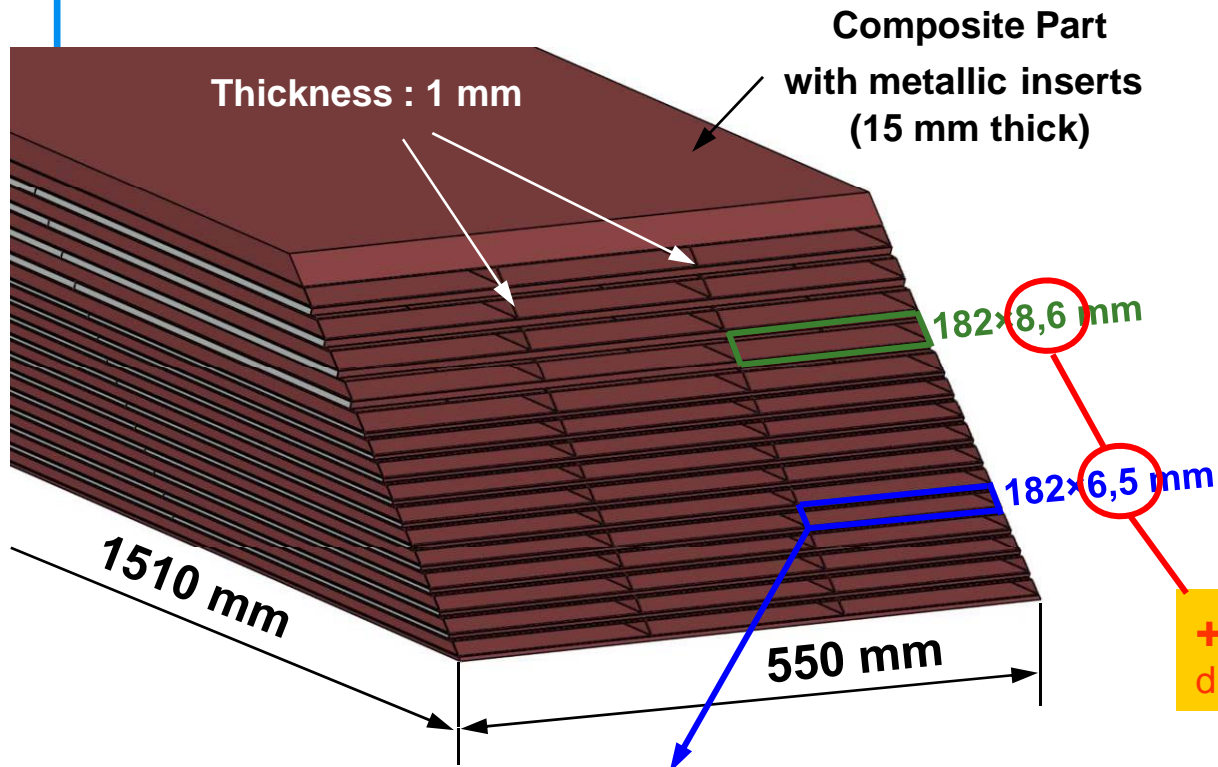
Physical prototype



- 3 structures : **24 X₀**
(10×1,4mm + 10×2,8mm + 10×4,2mm)
- sizes : **380×380×200 mm³**
- Thickness of slabs : **8.3 mm** (W=1,4mm)
- VFE **outside** detector
- Number of channels : **9720** (10×10 mm²)
- Weight : **~ 200 Kg**

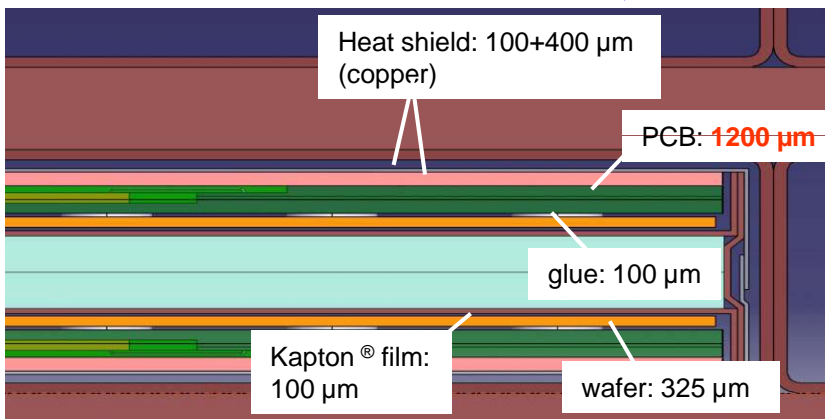
- 1 structure : **~ 23 X₀**
(20×2,1mm + 9×4,2mm)
- sizes : **1560×545×186 mm³**
- Thickness of slabs : **6.8 mm** (W=2,1mm)
- VFE **inside** detector
- Number of chan. : **~37890** (5.5×5.5 mm²)
- Weight : **~ 700 Kg**

EUDET - Current design



Thickness :
 FEV5-1 : 1.17mm (+0.04)
 FEV5-2 : 1.19mm (+0.04)
 FEV5-3 : 1.20mm (+0.02)

+ 0.8 mm !!!
 due to real PCB thickness

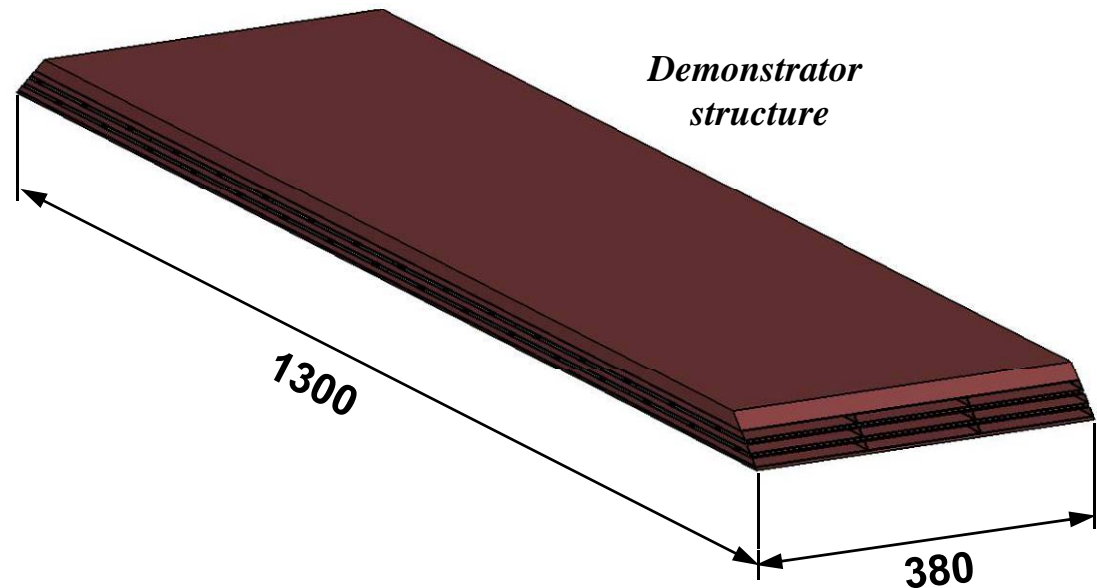


- ⇒ Gaps (slab integration) : 500 μm
- ⇒ Heat shield : 400 μm ? Validation by the demonstrator
- ⇒ PCB : ~~800 μm~~ → 1200 μm
- ⇒ Thickness of glue : 100 μm
- ⇒ Thickness of wafer : 325 μm
- ⇒ Kapton® film HV : 100 μm ? (Need to be tested)
- ⇒ Thickness of W : 2100/4200 μm (± 80 μm)

Demonstrator - Design

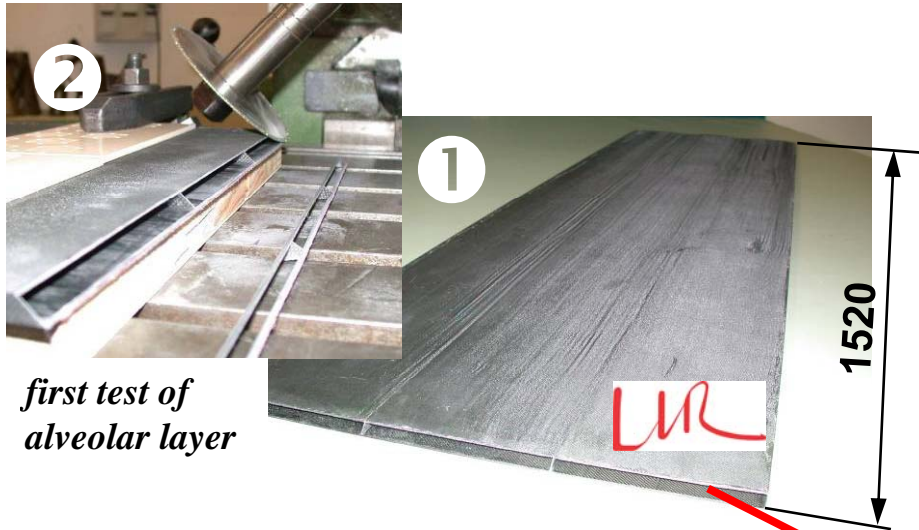
- We plan to build a first **small demonstrator** to validate all composite process before the EUDET module
- Width based on physic prototype (124 mm)
➡ designed before the validation of all Eudet dimensions !!!
- Could be used for **thermal studies** and analysis : design of a thermal PCB and cooling system close to EUDET design
- First test of **slab integration** (with gluing, interconnection ...)

- **3 alveolar layers + 2 W layers**
- **3 columns of cells : representative cell in the middle of the structure**
- **Thermal studies support**
- **Width of cells : 126 mm**
- **Identical global length : 1.3m and shape (trapezoidal)**
- **Fastening system ECAL/HCAL**

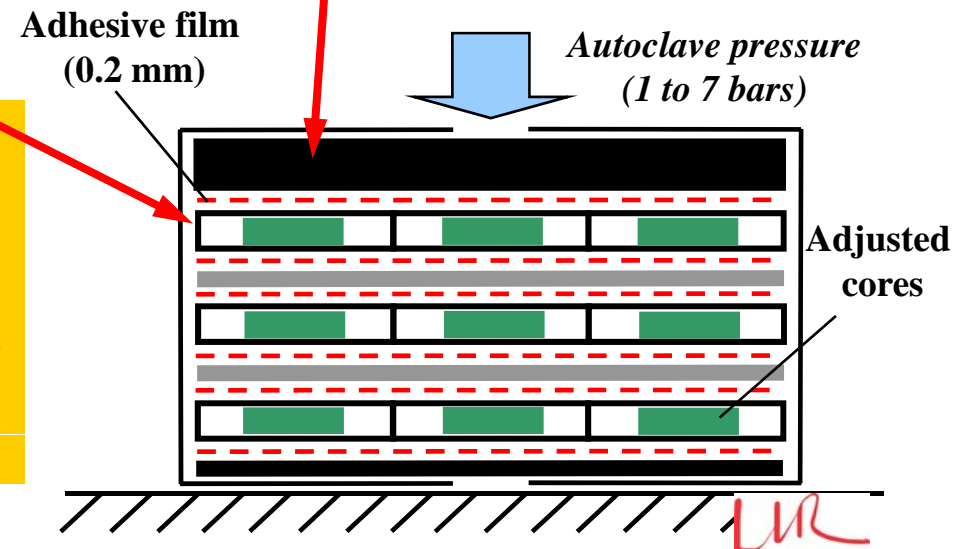


Demonstrator – Alveolar structure

Assembled structure : Each alveolar layer ❶ are done *independently* , *cut* to the right length and angle (❷) and *bonded* alternatively with W plates in a second curing step. The assembling is closed by 2 composite plates ❸ of 15 mm and 2 mm thick (from LPSC)



top composite plate (15mm)

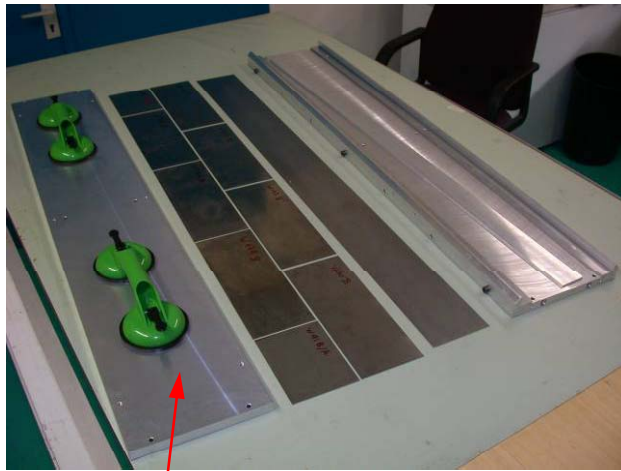


- ⇒ Global design : **OK**
- ⇒ "Alveolar layer" first test ❶ : **OK**
- ⇒ Cutting test ❷ : **OK**
- ⇒ Composite plates ❸ (15mm and 2 mm) : **OK**
- ⇒ Design assembling mould : **on going**

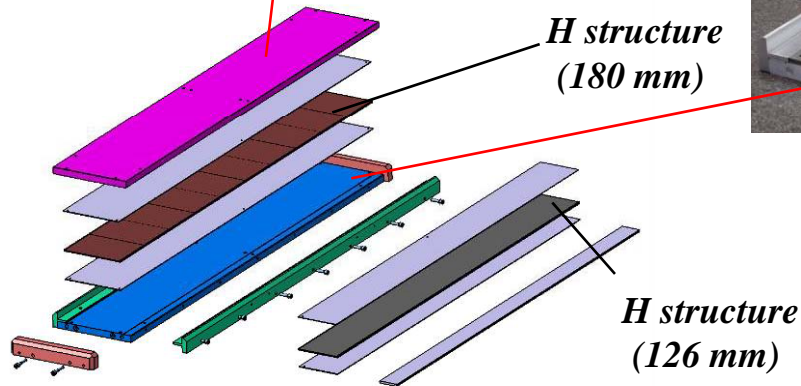
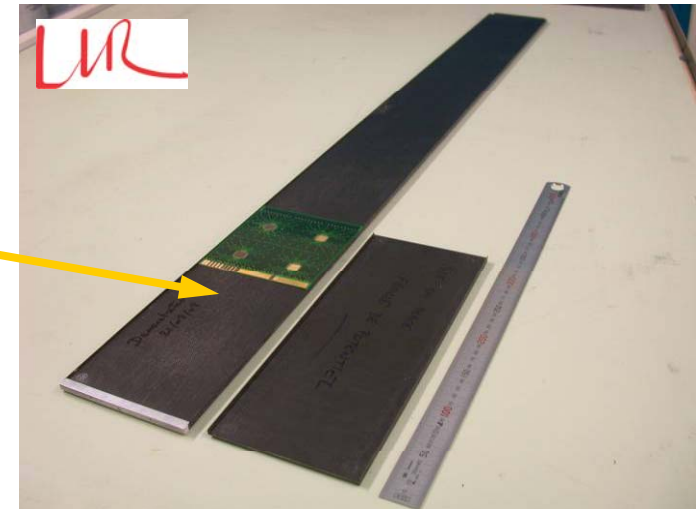
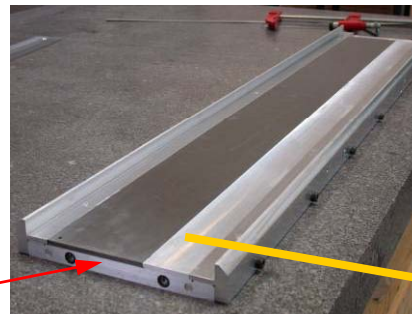
Demonstrator - H structure

Study of one mould for whole structures:

- Same principle than the mould used to do H physical prototype structures but using the autoclave)
- One long mould for both long and short H structures and 2 width (124 and 180 mm)



⇒ Design : *OK*
⇒ machining : *OK*
⇒ first H structure (1300×124): *OK*

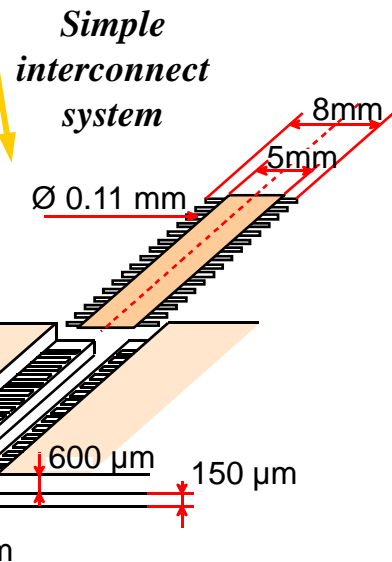
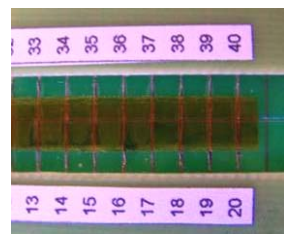
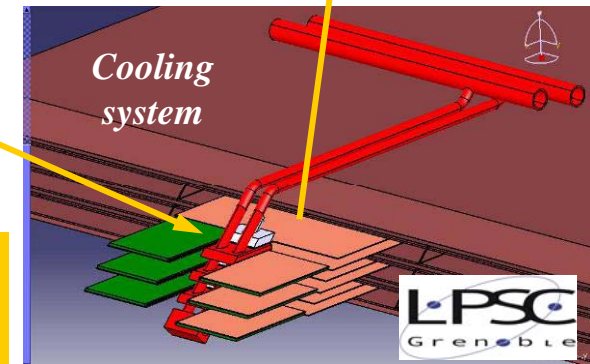
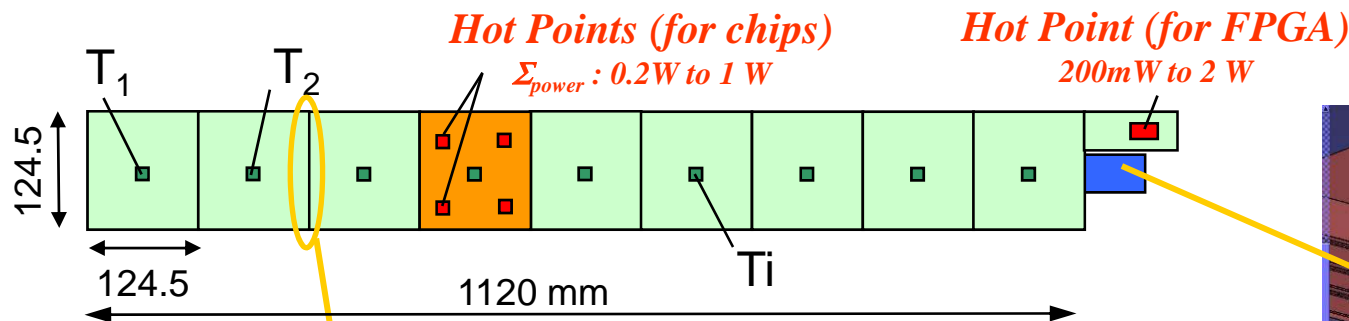


Demonstrator – Thermal studies

Slab cooling tests (1 Hot ASU + 8 thermal ASU):

- Correlation with **simulations** (transfer coefficients, contacts ...)
- Check a thermal dissipation behaviour close to **EUDET design**
- Validate **the cooling system** (400 μm copper plate drain + pipes)

Copper (400 μm)



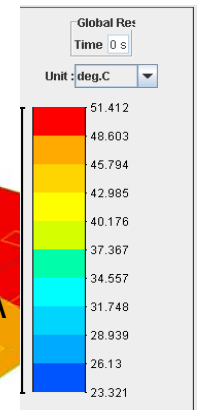
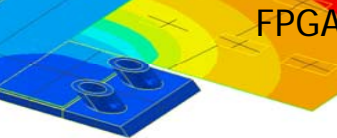
- ⇒ Design : **OK**
- ⇒ Simulations : **OK**
- ⇒ PCB : **on going**
- ⇒ Copper plate : **on going**
- ⇒ Interconnect : **on going**
- ⇒ Exp. setup : **on going**

Load case (exemple)

DIF



full amplitude : 28.5 $^{\circ}\text{C}$
ship amplitude : 12 $^{\circ}\text{C}$



Load case 2 : copper 0,4mm; SHIP power : 0.205 W;
FPGA power : 2 W distributed : 55 x 77.5 (KAPTON)

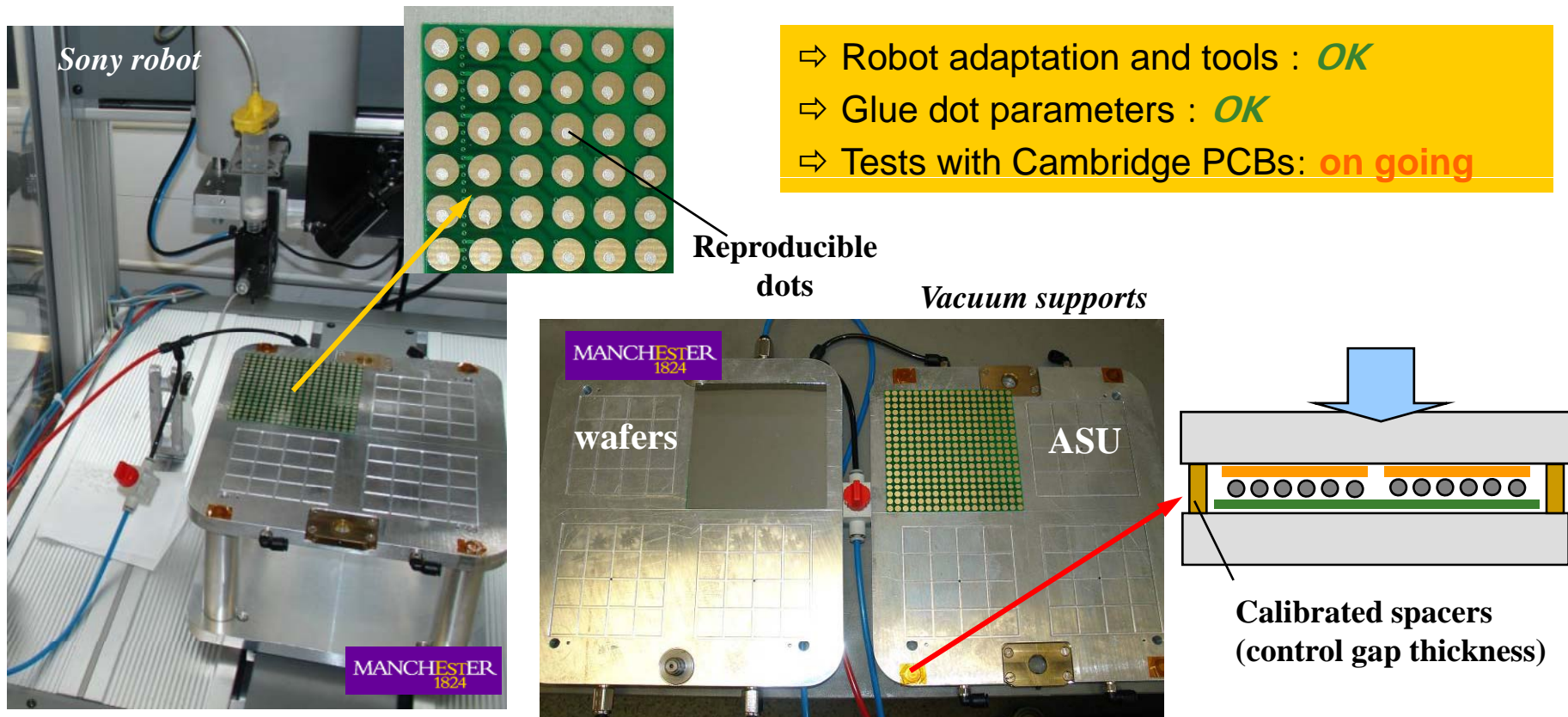
EUDET – Gluing of ASU

Principle is close to the physics prototype :

- Sony Robot and precision **glue dispenser tool** (glue: EPO-TEK® 4110)

But more industrial:

- **Vacuum system** to hold PCBs and wafers during all operations
- Alignment of wafer and PCB pixels using a **viewing system**



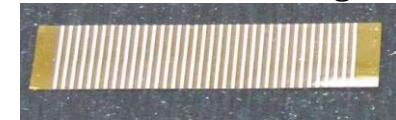
EUDET – Interconnect system

- Use “Bridges” principle to link multiple connections (30-40 each) between all adjacent ASUs (embedded in the thickness)
- Different designs tested: Short Flat Flexible Cable (electrical joint)

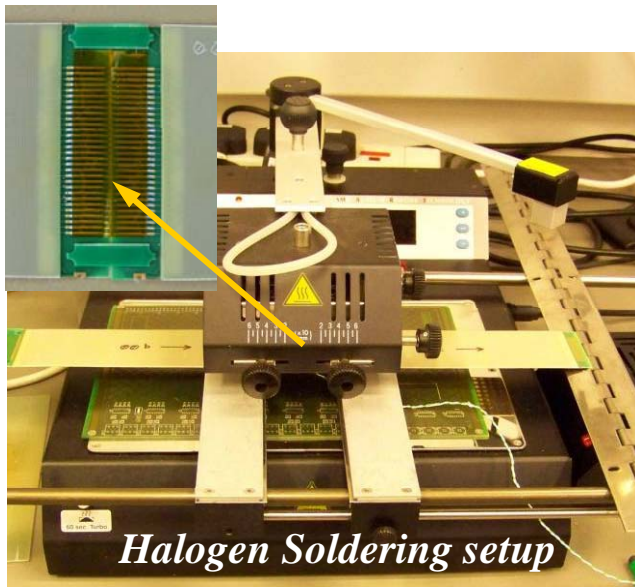
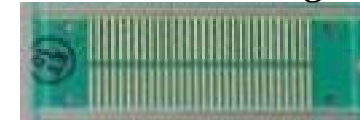
Thin PCB (electrical & mechanical joint)

- Thermal Bonding process investigations :
 - good electrical behaviour (voltage drop, crosstalk)
 - Use Soldering setup with no stress and damage for wafers (temp & pressure parameters)
 - Remove and rework the joint (dismounting aspect)

FFC bridge

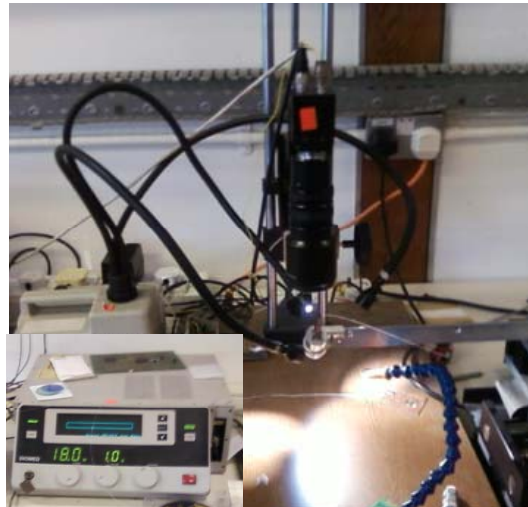


PCB bridge








Halogen Soldering setup

Laser soldering setup



- ⇒ Bridges design : **OK**
- ⇒ First bondings (FFC & PCB): **OK**
- ⇒ Electrical tests: **on going**
- ⇒ Re-flow system: **OK**
- ⇒ Interconnect of ASU: **on going** (with wafers glued)

Schedule

Gluing tests:		
	Thermal ASUs	Nov 08
	with EUDET ASUs prototypes	Dec 08
	of EUDET wafers (Hamamastu)	Dec 08
	Assembling mould design and fabrication	Nov 08
	Demonstrator (3 layers – 126 mm)	Dec 08
	EUDET module structures :	
	design needs to be fixed	Now !!!
	Final moulds design and order	Nov 08
	Copper drain & shield design and fabrication	Nov 08
	Integration slab tools for demonstrator and assembling	Nov 08
	Thermal slab	Dec 08
	Experimental setup for demonstrator	Oct 08
	Cooling pipes for EUDET	Nov 08
	Updated numerical simulations for demonstrator	Oct 08
	Soldering setup parameters (pressure, temp)	Oct 08
	Interconnection tests on ASUs + wafers	Dec 08